

# MICRONANO

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## MMC Activities

### MicroNano 2007 Report

MicroNano 2007 was held from Wednesday, July 25 through Friday, July 27, 2007, with the Tokyo International Exhibition Center (Tokyo Big Sight) in Ariake, Tokyo as the main venue. The exhibition was a resounding success, and the sponsors would once again like to express their appreciation to all who attended.

Like last year, MicroNano 2007 was a joint event in which the exhibition, conference and other events were held concurrently. This year's events attracted more than 12,000 visitors, the highest attendance yet. One noteworthy change from previous years was that the name of the exhibition was changed from Exhibition Micromachine to Exhibition

Micromachine/MEMS and a new MEMS device zone was provided. The conference was centered on the 13<sup>th</sup> International Micromachine / Nanotech Symposium, held in the "Iris" banquet room at the Tokyo Bay Ariake Washington Hotel. The conference events also included a MEMS Forum, held to encourage the development of MEMS-related industries and the adoption of MEMS international standards, and a seminar to announce the interim achievements of the Fine MEMS Project. Each of these events attracted a huge audience, leaving standing room only. This response is indicative of the high level of interest in micro-nano fields that continues to increase each year.

### 18<sup>th</sup> Exhibition Micromachine/MEMS: A Resounding Success

For three days (July 25 - 27, 2007), the 18<sup>th</sup> Exhibition Micromachine/MEMS was held in the West Hall No. 3 and 4 at the Tokyo International Exhibition Center (Tokyo Big Sight) in Ariake, Tokyo. Although Japan's hot, muggy summer was nearly at its height, the event was favored by excellent weather, and it was a resounding success.

Up until last year, the event was titled Exhibition



Micromachine. This year, the name was changed to Exhibition Micromachine/MEMS to better reflect the content of the products shown by exhibitors. Moreover, this year a special MEMS Device Zone was set up to enable visitors to view the many different devices that employ MEMS in a single location.

With the heightened interest in micromachine/MEMS technologies, the exhibition has grown in scale each year. The exhibitors at this year's event included 14 companies that are supporting members of the Micromachine Center and five companies that are associate members of the MEMS Industry Forum. Other exhibitors included private companies, universities, independent administrative agencies and so on. The total number of exhibitors set a new record: 362 companies, organizations, universities and research institutions in 484 booths. This total included 14 overseas companies.

Attendance during the three days of the exhibition was more than 12,424, also a new record.

#### 19<sup>th</sup> Exhibition Micromachine/MEMS (tentative)

**Date/time :** Wednesday, July 30 - Friday, August 1, 2008

**Venue :** West Hall No. 1 & 2, Tokyo International Exhibition Center (Tokyo Big Sight), Ariake, Tokyo

### MEMS Forum

The MEMS Forum was held on July 25, 2007 at a special venue set up within the West No. 3 Hall at Exhibition Micromachine/MEMS. The purpose of the Forum was to achieve an enhanced common recognition of issues involved in the development of MEMS-related industries.

At the MEMS Forum, case studies of activities were presented from three perspectives: MEMS personnel infrastructure, MEMS design infrastructure and MEMS manufacturing infrastructure. All of these are issues that will lead to a strengthening of the MEMS industrial base. In addition, a report on academic activities was also presented

from the perspective of industrial-academia collaboration, which will support the growth of MEMS industries. A report on research projects conducted by the Micromachine Center and the MEMS Industry Forum was also presented.

In connection with efforts by the MEMS Industry Forum to build cooperative relationships with related overseas MEMS organizations, this year the special focus was on Asia. An Asia MEMS Forum session was held at which delegates from South Korea, China and Taiwan reported on trends in MEMS industry and technology in their countries.